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United States Patent [19]

Flamm [45] Date of Patent: Jan. 25, 2000

[11]

[54] PROCESS DEPENDING ON PLASMA DISCHARGES SUSTAINED BY INDUCTIVE COUPLING

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Related U.S. Application Data

[63] Continuation-in-part of application No. 08/736,315, Oct. 23, 1996, abandoned, which is a continuation of application No. 08/567,224, Dec. 4, 1995, abandoned.

[51] Int. Cl.⁷ H01L 21/00

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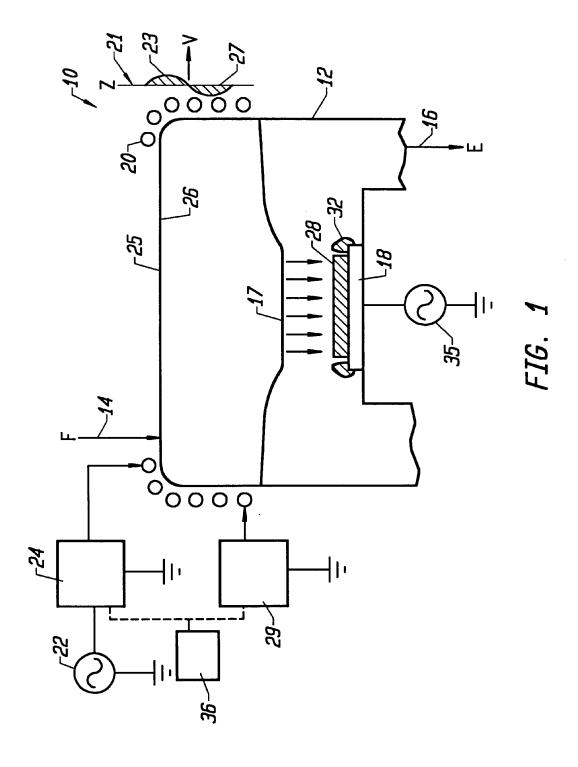
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[57] ABSTRACT

A process for fabricating a product 28, 119. The process comprises the steps of subjecting a substrate to a composition of entities, at least one of the entities emanating from a species generated by a gaseous discharge excited by a high frequency field in which the vector sum of phase and anti-phase capacitive coupled voltages from the inductive coupling structure substantially balances.

7 Claims, 13 Drawing Sheets







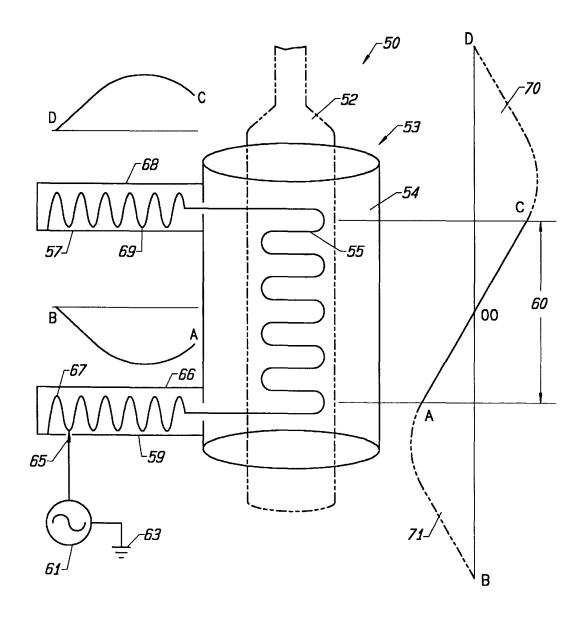
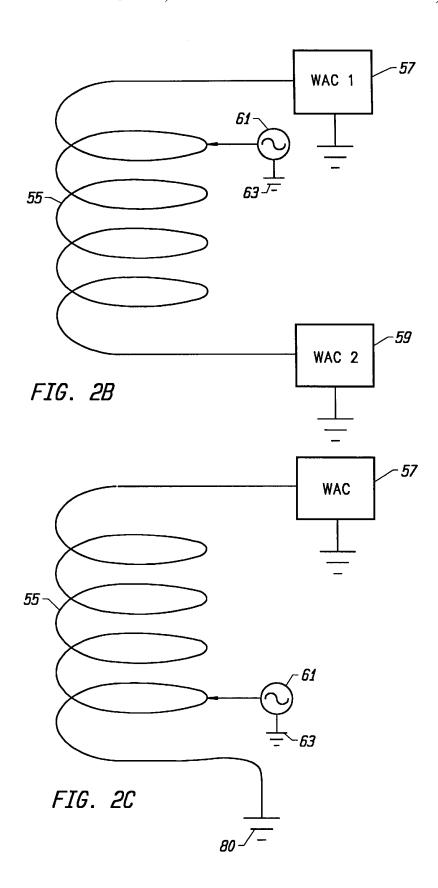


FIG. 2A



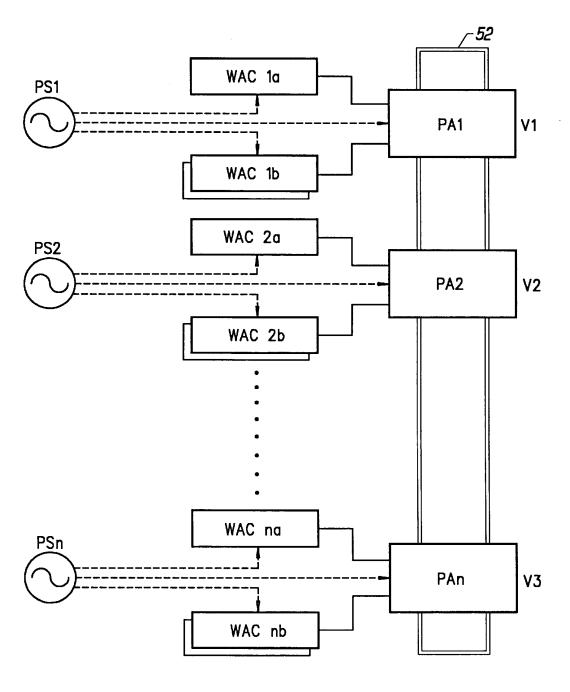


FIG. 2D

DOCKET

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